IN THE CLAIMS:

Please amend the claims as follows. This listing of the claims will replace all prior versions, and listings, of claims in the application:

1-14 (Canceled)

15. (Previously Presented) A gas cooking apparatus, comprising:
at least one gas burner;
a control system for adjusting the heat output of said gas burner;
said control system including at least one control organ arranged in a gas main leading to said gas burner;
said control system controls said control organ to adjust a gas throughput supplied to a burner nozzle of said gas burner;
at least one primary line communicated with the gas main and coupled to said burner nozzle via said control organ such that said control organ controls the gas throughput supplied through said primary line to said burner nozzle and the path of gas supplied through said primary line via said control organ to said burner nozzle having a flow resistance greater than a flow resistance formed by said burner nozzle;
at least one secondary line coupled to said burner nozzle in parallel to said control organ;
said secondary line including an allocated shut-off organ for opening and closing said secondary line; and
said secondary line formed to have a flow resistance which restricts the gas throughput in said secondary line, said flow resistance lower than a flow resistance formed by said burner nozzle.

16. (Previously Presented) The gas cooking apparatus according to claim 15, including said secondary line flow resistance which restricts said gas throughput is formed by the smallest transmission cross-section in said secondary line and said primary line flow resistance which restricts said gas throughput is formed by the smallest transmission cross-section in said primary line.

17. (Previously Presented) The gas cooking apparatus according to claim 16, including said smallest transmission cross-section in said secondary line is larger than the transmission cross-section of said burner nozzle.

18. (Previously Presented) The gas cooking apparatus according to claim 16, including said secondary line is open at least when a maximum gas throughput is set.

19. (Previously Presented) The gas cooking apparatus according to claim 18, including said secondary line is closed when a partial gas throughput is set and said secondary line is only open when said maximum gas throughput is set.

20. (Previously Presented) The gas cooking apparatus according to claim 15, including said shut-off organ for opening and closing said secondary line is constructed as an unthrottled control valve and said primary line including an allocated shut-off organ for opening and closing said primary line.

21. (Previously Presented) The gas cooking apparatus according to claim 15, including said control system including a plurality of control organs, said control organs provided in a plurality of separate control lines branching

off from said gas main and said control organs switched in parallel to one another.

22. (Previously Presented) The gas cooking apparatus according to claim 21, including said control lines and said secondary line are constructed in a common housing.

23. (Previously Presented) The gas cooking apparatus according to claim 21, including said control and said secondary lines each have a mounting opening in said common housing for inserting said control organs.

24. (Canceled)

25. (Previously Presented) The gas cooking apparatus according to claim 21, including said mounting opening of said secondary line is closed by a closure element.

26. (Previously Presented) The gas cooking apparatus according to claim 21, including said control system is designed so that a plurality of part gas throughputs (Q_1 to Q_7) increase up to about sixty percent (60%) of a maximum gas throughput (Q_8) in a substantially constant first increase.

27. (Previously Presented) The gas cooking apparatus according to claim 26, including in a second increase said part gas throughputs (Q_1 to Q_7) increase from about sixty percent (60%) of said maximum gas throughput (Q_8) to said maximum gas throughput (Q_8) which is greater than said first increase.

28. (Previously Presented) The gas cooking apparatus according to claim 21, including when a maximum gas throughput (Q_8) is set, said gas main, especially said control lines branching off from said gas main, are open.

29. (Canceled)

30. (Canceled)

31. (Canceled)

32. (Canceled)

33. (Previously Presented) The method according to claim 32, including closing said secondary line when a partial gas throughput is set and only opening said secondary when said maximum gas throughput is set.

34. (Previously Presented) The method according to claim 29, including forming said shut-off organ for opening and closing said secondary line as an unthrottled control valve.

35. (Previously Presented) The gas cooking apparatus according to claim 20, including said control system including a plurality of control organs, said control organs provided in a plurality of separate control lines branching off from said gas main and said control organs switched in parallel to one another.

36. (Currently Amended) A gas cooking apparatus, comprising:
at least one gas burner;
a control system for adjusting the heat output of said gas burner;

said control system including at least one control organ arranged in a gas main leading to said gas burner;
said control system controls said control organ to adjust a gas throughput supplied to a burner nozzle of said gas burner;
at least two primary lines communicated with the gas main and coupled to said burner nozzle via said control organ such that said control organ controls the gas throughput supplied through each of said primary lines to said burner nozzle, each of said primary lines forming a path of gas and the path of gas supplied through each one of said primary lines via said control organ to said burner nozzle having a flow resistance greater than a flow resistance formed by said burner nozzle;
at least one secondary line coupled to said burner nozzle in parallel to said control organ;
said secondary line including an allocated shut-off organ for opening and closing said secondary line; and
said secondary line formed to have a flow resistance which restricts the gas throughput in said secondary line, said flow resistance of said secondary line being lower than a flow resistance formed by said burner nozzle, said control system controlling said control organ to adjust a gas throughput supplied to said burner nozzle supplying gas to a burner nozzle of a gas burner via said at least two primary lines, whereupon the respective gas supplied through each respective primary line communicated with said burner nozzle is less than a maximum gas throughput that could be handled by said burner nozzle and controlling gas supplied via said at least two primary lines such that the collective gas throughput through all primary lines is less than the maximum gas throughput that could be handled by said burner nozzle and said control system selectively supplying gas to said burner nozzle via said secondary line at a time during which said supplying gas via said at least two primary

lines occurs, whereupon the total gas supplied to said burner nozzle during such simultaneous supplying of gas via said at least two primary lines and via said secondary line is at least equal to the maximum gas throughput that could be handled by said burner nozzle.

37. (New) A method for controlling a gas cooking apparatus including at least one gas burner, the method comprising:

supplying gas to a burner nozzle of a gas burner via a primary gas route, said supplying gas via a primary gas route including supplying gas through at least one primary line communicated with said burner nozzle and having a flow resistance greater than a flow resistance formed by said burner nozzle, whereupon the respective gas supplied through each respective primary line communicated with said burner nozzle is less than a maximum gas throughput that could be handled by said burner nozzle and controlling gas supplied via said primary gas route such that the collective gas throughput through all primary lines is less than the maximum gas throughput that could be handled by said burner nozzle; and

selectively supplying gas to said burner nozzle via a secondary gas route, said selectively supplying gas via said secondary gas route including supplying gas through a secondary line having a flow resistance lower than a flow resistance formed by said burner nozzle and supplying gas through said secondary line at a time during which said supplying gas via said primary gas route occurs, whereupon the total gas supplied to said burner nozzle during such simultaneous supplying of gas via said primary

gas route and via said secondary gas route is at least equal to the maximum gas throughput that could be handled by said burner nozzle.

38. (New) The method according to claim 37, wherein said selectively supplying gas via said secondary gas route includes supplying gas through a secondary line which restricts said gas throughput by the smallest transmission cross-section among said primary line and said secondary line.

39. (New) The method according to claim 37, wherein said selectively supplying gas via said secondary gas route includes supplying gas through a secondary line whose cross-section is the smallest transmission cross-section among said primary line and said secondary line and this transmission cross-section in said secondary line is larger than the transmission cross-section of said burner nozzle.